

INFORMATION DISCLOSURE CITATION

Page 1 of 2 Pages



Docket: 015559-238

Serial No.: 09/833,174

Applicant: James W. Siekkinen et al.

Filed: 4/11/01

Group: 2816

U.S. PATENT DOCUMENTS

Examiner	Document No.	Date	Name	Class	Sub	
RB	4,618,840	10/86	Yee et al.	—	—	
RB	5,808,384	09/98	Tabat et al.	—	—	
RB	5,994,159	11/99	Aksyuk et al.	—	—	
RB	5,994,982	11/99	Kintis et al.	—	—	
RB	5,995,688	11/99	Aksyuk et al.	—	—	
RB	6,020,564	02/00	Wang et al.	—	—	
RB	6,046,659	04/00	Loo et al.	—	—	
RB	6,061,025	05/00	Jackson et al.	—	—	
RB	6,069,540	05/00	Berenz et al.	—	—	
RB	6,094,293	07/00	Yokoyama et al.	—	—	
RB	6,097,859	08/00	Solgaard et al.	—	—	
RB	6,100,477	08/00	Randall et al.	—	—	
RB	6,134,207	10/00	Jerman et al.	—	—	

FOREIGN PATENT DOCUMENT

							Trans	
Examiner	Document No.	Date	Country	Class	Sub		Y	N
Examiner: <u>Banera</u>		Date Considered: <u>11/28/03</u>						

* Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

INFORMATION DISCLOSURE CITATION

Page 2 of 2 Pages



Docket: 015559-238

Serial. No.: 09/833,174

Applicant: James W. Siekkinen et al.

Filed: 4/11/01

Group: 2816

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

RB	Miller, R.A., et al., Electromagnetic MEMS Scanning Mirrors, Electrical Engineering, MS136-93, California Institute of Technology (no date). Admitted to be prior art for the limited purpose of examination of this application; applicants reserve the right to challenge the status of this paper as prior art.
RB	Miller, R.A., et al., Magnetically Actuated Micromirrors for Use as Optical Deflectors, Electrical Engineering, MS116-81, California Institute of Technology (no date). Admitted to be prior art for the limited purpose of examination of this application; applicants reserve the right to challenge the status of this paper as prior art.
RB	Comtois, J.H., et al., Characterization of Electrothermal Actuators and Arrays Fabricated in a Four-Level, Planarized Surface-Micromachined Polycrystalline Silicon Process, Transducers '97, 1997 International Conference on Solid-State Sensors and Actuators (6/97).
RB	Hosaka, H., et al., Electromagnetic Microrelays: Concepts and Fundamental Characteristics, 1993 IEEE (2/93).
RB	Hyman, D., et al., Contact Physics of Gold Microcontacts for MEMS Switches, IEEE Transactions on Components and Packaging Technology, Vol. 22, No. 3. (9/99).
RB	Majumder, S., et al., Electrostatically Actuated Micromechanical Switches, J. Vac. Sci. Technol. A 15(3) (5/97).
RB	Statement (including Attachments A-D).
Examiner: <u>Barren</u> Date Considered: <u>11/28/03</u>	

* Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

NOV 11 2003